MAR 1 9 2006

M. ROBERT KESTENBAUM, LLC PATENT AND TRADEMARK MATTERS

FACSIMILE TRANSMITTAL SHEET	
10: Examiner Trinh, Art Unit 3729	from: M. Robert Kestenbaum
COMPANY: Commissioner for Patents	March 19,. 2006
FAX NUMBER: (571) 273 4569 (571) 273 8300	TOTAL NO. OF PAGES INCLUDING COVER: 4
PHONE NUMBER: (571) 272 4569	sender's reference number: (H) 02ID0374USP
Request for Examiner's Amendment	YOUR REFERENCE NUMBER: 10/613,870

NOTES/COMMENTS:

Dear Examiner Trinh:

I am faxing this request for you to complete an Examiner's Amendment to the specification to correct clerical errors in the specification. These changes do not add new matter, but rather, merely conform the description to the specifications set forth in the priority document. Thank you in advance for completing an Examiner's Amendment to correct these errors, and for using these specifications in your continued examination of this application.

Thank you for considering this submission.

Sincerely,

M. Robert Kestenbaum

Reg. No. 20,430

BEST AVAILABLE COPY

03/19/2006 18:17 FAX 5053230865

M OBERT KESTENBAUM

RECEIVED
CENTRAL FAX CENTER

Ø 002

MAR 19 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re: US Patent Application 10/613,870

Applicant

Heiland

Art Unit

3729

Examiner

Minh Trinh

Examiner's Phone

(571) 272-4569

Attorney Docket

(H)02ID0374USP

Mail Stop Amendment PO Box 1450 Commissioner for Patents Alexandria, Va. 22313-1450

Request for Examiner's Amendment

Dear Examiner Trinh:

This is submitted in further response to the Office Action mailed 11/01/2005. In reviewing the specification, we found further typographical errors in the specification, which we request you change by Examiner's Amendment. These errors were in paragraphs 0023, 0025, and 0039. The changes we are requesting you make do not add new matter, but merely conform the description to the specifications set forth in the priority document. Thank you in advance for completing an Examiner's Amendment to make these corrections to the specification.

In the specification:

[0023] In an embodiment, the electrode pairs are arranged at a distance from one another in such a way that the wafer can be gripped at the edge. In this way, the advantages of the compact structure of the electrode pairs are optimally utilized. The edge-side gripping allows heating in sensitive regions of the wafer to be reduced still further. For lifting purposes, according to a further embodiment the gripper has three electrode pairs that are arranged on a circular path, ideally at 120 angles degrees around

Heiland (H)02ID0374USP; US Patent Application 10/613,870 Amendment responding to Office Action mailed 11/01/2005 Submitted by fax on 01/30/2006